

Docket No.: 006301 USA/Consilium/Consilium/DK

Image 2812
PATENT/OFFICIAL \$

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Badri N. KRISHNAMURTHY et al.

Serial No. 09/928,474

Filed: August 14, 2001

For: EXPERIMENT MANAGEMENT SYSTEM, METHOD AND MEDIUM

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: Group Art Unit: 2812
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: Examiner: Andre' C. Stevenson

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document.

12/23/2003 RHEBRAHT 00000146 080219 09928474

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Serial No. 09/928,474

Please charge the fee of \$180.00 under 37 CFR 1.17(p) to Deposit Account No. 08-0219.

The Commissioner is hereby authorized to charge any additional fees that may be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

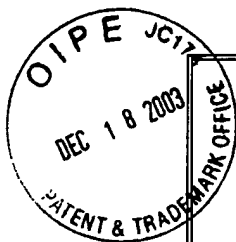
HALE AND DORR LLP

A handwritten signature in black ink, appearing to read "Scott M. Alter", written in a cursive style.

Scott M. Alter

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Date: 12/18/05



**INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION
(PTO-1449)**

ATTY. DOCKET NO.
006301
USA/Consilium/Consilium/
DK

SERIAL NO.
09/928,474

APPLICANT
Badri N. KRISHNAMURTHY et al.

FILING DATE
August 14, 2001

GROUP
2812

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	4,207,520	06/10/80	Flora et al.			04/06/78	
	4,209,744	06/24/80	Gerasimov et al.			03/27/78	
	4,609,870	09/02/86	Lale et al.			09/13/84	
	4,755,753	07/05/88	Chern			07/23/86	
	5,427,878	06/27/95	Corliss			05/16/94	
	5,534,289	07/09/96	Bilder et al.			01/03/95	
	5,867,389	02/02/99	Hamada et al.			11/26/96	
	6,041,263	03/21/00	Boston et al.			10/01/97	
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	6,271,670	08/07/01	Caffey			02/08/99	
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	6,587,744	07/01/03	Stoddard et al.			06/20/00	
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	WO 01/11679	02/15/01	WIPO			X	
	WO 01/080306	10/25/01	WIPO			X	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 – 805.
	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." www.Lehighton.com/fabtech1/index.html .
	2000. "Microsense II Capacitance Gaging System." www.adetech.com .
EXAMINER	DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.



INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 006301 USA/Consilium/Consilium/ DK		SERIAL NO. 09/928,474	
				APPLICANT Badri N. KRISHNAMURTHY et al.			
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation Yes No	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 – 1296.						
	March 5, 2001. "KLA-Tencor Introduces First Production-worthy Copper CMP In-situ Film Thickness and End-point Control System." http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74 .						
	2002. "Microsense II – 5810: Non-Contact Capacitance Gaging Module." www.adetech.com .						
	08 August 2003. PCT International Search Report from PCT/US03/08513.						
	14 October 2003. PCT International Search Report from PCT/US02/21942.						
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	"ADE Technologies, Inc. – 6360." http://www.adetech.com/6360.shtml .						
	"3D optical profilometer MicroXAM by ADE Phase Shift." http://www.phase-shift.com/microxam.shtml .						
	"NanoMapper FA factory automation wafer nanotopography measurement." http://www.phase-shift.com/nanomapperfa.shtml .						
EXAMINER				DATE CONSIDERED			

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